Amendments to the Specification

On page 4, please replace the paragraph spanning lines 3-8 with the following replacement paragraph:

It is an object of the present invention on the one hand to maintain the principal tower structure concept as of the ~~US 275 709~~ US 5 275 709 for large substrate processing thereby further improving simplicity of substrate handling and improving flexibility with respect to treating such substrates by well defined multiple steps substrate processing.

Please cancel the **three** paragraphs spanning page 22 line 25 to page 24 line 10, and insert the following **three** replacement paragraphs therefor:

According to Fig. 14 there is provided within the vacuum chamber of the transport arrangements (not shown) a stationary central support post 13. For handling large substantially flat and horizontally positioned substrates 3a with respect ~~tom~~ to the LLPT 1a of Fig. 12 and 13, at the one side of post 13 there is provided a first sliding arrangement 14a which is vertically slideable - va - in controlled driven manner. Mounted to sliding arrangement 14a there is provided a number of single substrate supporting member 15a, as shown e.g. three. They project horizontally and are vertically mounted distant ~~form~~ from each other and, in one preferred embodiment, with a controllably variable pitch distance p_a. Thus the pitch distance p_a in this preferred embodiment may be controllably varied, e.g. to accommodate for substrate handling openings at the LLA and/or PMA with different vertical pitch distances

Each of the supporting members 15a may be expanded and retracted horizontally - h -, driven by telescopic drives, as shown within encapsulations 17a. The supporting members 15a have supports with supporting pins 20 whereupon the substrates 3a to be processed in LLPT 1a are disposed during horizontal and vertical transport. There is further provided a second sliding arrangement 14b opposite sliding arrangement 14a along post 13, which is ~~construed~~ constructed with supporting members 15b, supports 19b supporting pins 20b, encapsulates 17b very much like the arrangement mounted on slide 14a whereby, as shown, the number of supporting members 15b which do handle substrates 3b with respect to LLPT 1b as of figure 12 or 13 needs not to be equal with the number of members 15a for serving substrate 3a to be processed by a LLPT 1a.

Preferably, the horizontally movable supports ~~9a and 9b~~ 19a and 19b are ~~construed~~ constructed in a forklike manner as shown in Fig. 15. In dashed line representation, Fig. 15 shows a respective substrate 3a,b residing on the support 19a,b and being thereby deposited on support pins 21 in a LLA or PMA. With the second preferred embodiment as of Figs. 12 to 15 there is provided an apparatus according to the present invention with two distinct loadlock- and processing towers LLPT 1a and 1b which each provide for the complete set of modules to perform substrate processing inclusive feeding such substrate from surrounding atmosphere AT to the vacuum processing and from vacuum processing back to surrounding atmosphere.

Please cancel the paragraph on page 24 at lines 16-27, and insert the following replacement paragraph therefor:

As schematically shown in Fig. 14, a controlling unit [[21]] 22 is provided for controlling the horizontal transport movements $h_{a,b}$, the vertical transport movements $v_{a,b}$ with respect to their extent, timing of the respective horizontal and vertical transport cycles as well as, if necessary, pitch distance p_a of the respective support arrangements. Such a control unit [[21]] 22 is preferably realised as a free programmable unit so that in dependency of an intended processing especially timing of the transport cycles may flexibly be adapted. Such a controlling unit [[21]] 22 preferably also controls processing and loadlock cycles as schematically shown in Fig. 14 with the control connections to LLA_{ab} and PMA_{ab}.